Deep-Junction LGAD

A New Approach to Higher Granularity Fast Timing Detectors

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36th RD50 Workshop 2020-06-04





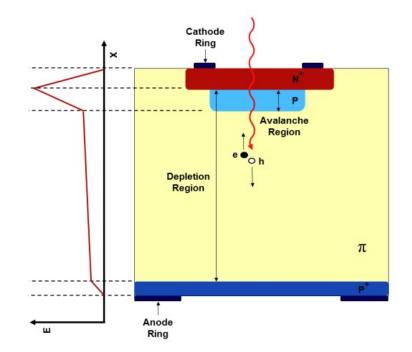


Overview

- Quick overview of Low Gain Avalanche Detectors (LGAD)
- Existing approaches for higher granularity LGADs.
- New approach to higher granularity LGADs: Deep-Junction LGADs (DJ-LGADs).
 - Updates for current stage of first prototype and simulation studies.

Low Gain Avalanche Detectors (LGADs)

- Silicon detector with highly doped thin multiplication layer (~10¹⁶ p++)
 - provide high electric field that's capable for avalanche effect to happen.
- Intrinsic modest internal gain (10-50):
 - Good signal to noise ratio.
- Allows thin active thickness (50 to 20 μm)
 - Short rise time
 - less Landau fluctuations.

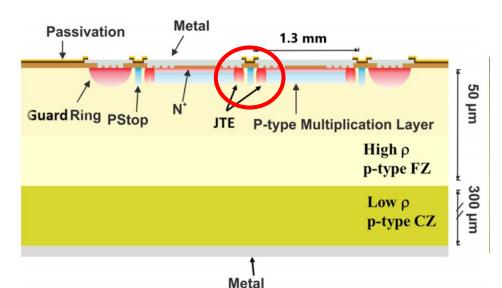


• Fast Timing resolution < 30ps

$$\sigma_{timing}^2 = \sigma_{time \, walk}^2 + \sigma_{Landau \, noise}^2 + \sigma_{Jitter}^2 + \sigma_{TDC}^2$$

Granularity Limitation of LGAD Arrays

- One of the current limitation of LGADs is achieving higher granularity.
 - Electrical insulation is required for LGAD array due to the high electric in the multiplication region.
 - Junction Termination Extension (JTE) is used between pads.
 - Inter pad gap 50 to 150μm.
 - Limits granularity to mm scale.
- The next generation colliders and 4D tracking detectors require sensors to have 50µm pitch (or less).

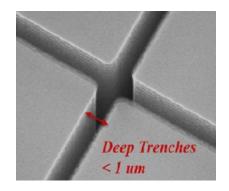


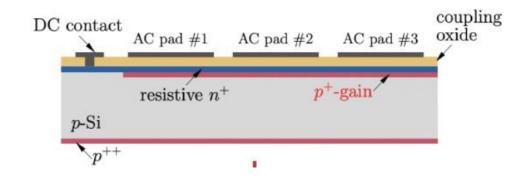
Existing Solutions for Higher Granularity

- Several promising approaches to increase granularity are proposed and under studying: 80 µm
 - 1) Inversed LGAD (iLGAD)
 - Reverse position of the gain layer



- AC coupling to the output
- 3) Trench Isolated LGAD (TI-LGAD)





P' (n)

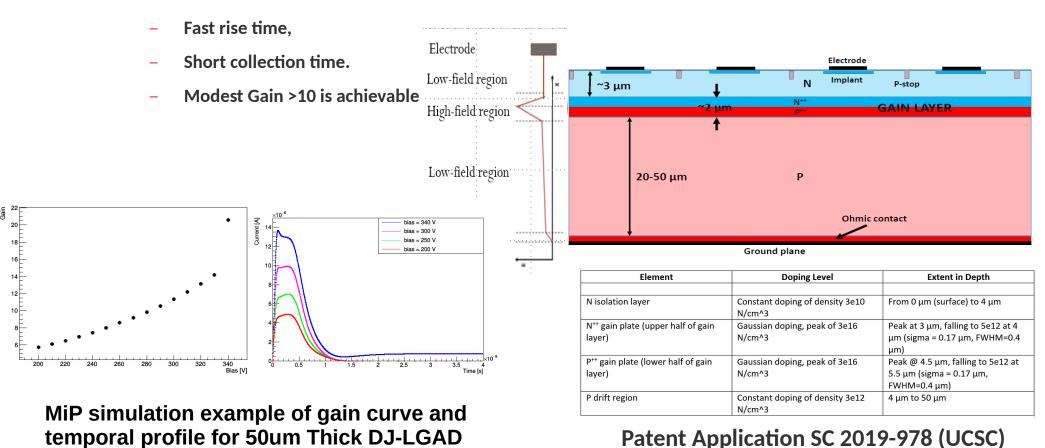
300 μm

New Approach: Deep Junction LGAD

- The idea of deep junction LGAD (DJ-LGAD) was first presented by S.Mazza
 - See links on TREDI2020, 15th Trento Workshop
 https://indico.cern.ch/event/813597/contributions/3727775/attachments/1989522/3316390/020220_TREDI_DJ_L GAD_smazza.pdf
 - We have received great feedback from the community, and updates on the sensor design will be shown in this presentation.
- Working principle and ideas of DJ-LGAD:
 - Localize the high electric field region within the sensors. Achieve by pairing p++ gain layer with n++ layer, and burying the junction ~5µm below the surface.
 - Addition of low doped n type substrate to lower the electric field near the surface. Allow usual (pixel) segmentation techniques to be used to increase granularity.
 - The n type substrate is DC coupling to the electrode.

New Approach: Deep Junction LGAD

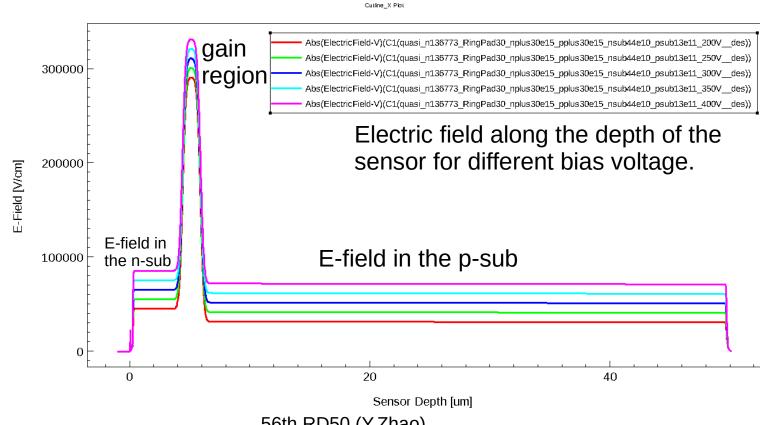
• Schematic and example of Sentaurus TCAD simulation result for the original design of 50μm DJ-LGAD (before additional studies reported)



C.Gee, S.Mazza, B.Schumm, Y.zhao

New Approach: Deep Junction LGAD

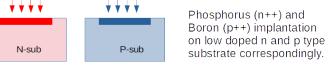
- The electric field along the depth of the sensor for different bias voltage is shown.
 - The multiplication/gain region (high field) is below the surface.
 - The addition of n type substrate bring the field down near the surface



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Current Stage of DJ-LGAD Design & Production Timeline

- We are making progress toward producing the first prototype in collaboration with Cactus Materials Inc. (AZ)
 - The production is fully funded by the DoE SBIR "A New Approach to Achieving High Granularity in Low Gain Avalanche Detectors" (34b).
 - Wafer design is starting soon:
 - Mask layout/design in a few weeks.
 - Finalizing parameters (doping, etc) during late Fall?
 - Have the first prototype by the end of the year.
 - Single pad planer device will be produced in phase-1:
 - The deep junction will be attempted by wafer-to-wafer bonding.
- BNL also planned for production of first DL-LGAD prototype.
 - The deep junction will be attempted with epi growth approach.
 - Probably have the prototype within a year.



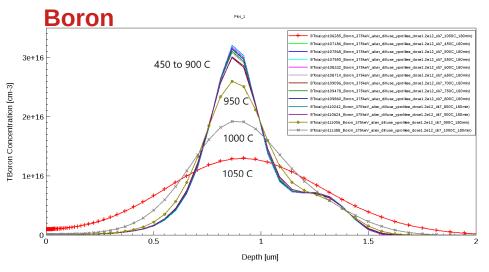
Wafer to wafer bonding.

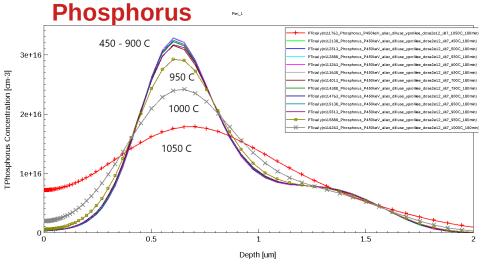


Etching the n substrate and putting electrodes and contacts

Current Stage of DJ-LGAD Implantation Energy, Annealing Temperature

- Annealing step will be done at the stage of wafer to wafer boding.
 - No anneal step after implantation.
- Simulated annealing effect with different temperature for Boron and Phosphorus (3 hrs)
 - Maximum annealing temperature of 900C will be used.
- Example of simulated implantation energy:
 - Boron: 375 keV → depth ~850nm, Phosphorus: 450 keV → depth ~600nm
- Implantation dosage is still under study.





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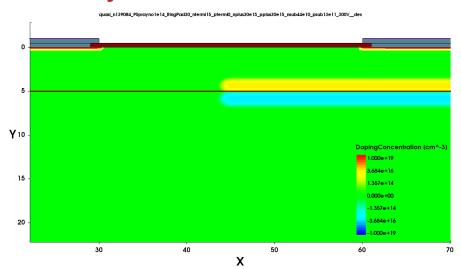
Current Stage of DJ-LGAD Edge Termination

- The question of gain layer (n++ & p++) termination from the edge of the sensor was raised.
 - As suggested to avoid any possible high electric field region near the physical edge of the sensors to avoid early breakdown.
- We have proposed some possible approaches:
 - Symmetric (right) or asymmetric (left) n++ and p++ with limited lateral extension.
 e.g. the edge n++ and p++ is ~40μm away in X from the edge of the sensor.

Asymmetric termination

Guard Ring Readout Pad 2 n-sub n++ p++ Y 6 DopingConcentration (cm^-3) 000e+19 3.684e+16 8 1.357e+14 0.000e+00 10 --1.357e+14 p-sub 12 -1.000e+19 20 80 X

Symmetric termination



Current Stage of DJ-LGAD Edge Termination

- Example of 2D electric field map for these two configurations are shown:
 - Color the indicates the value of abs(electric field)
 - The black lines are the electric field lines.

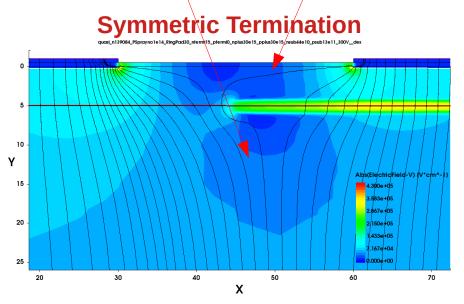
Asymmetric termination:

- the region above the excessive part of n++ has very low field, and a small non-depleted region.
- No field lines across.

Asymmetric Termination Qual_nes/64_BingPoc30_nterm20_pterm10_nplus30e18_pub430e18_nub444_10_psub13e11_300V__des Abs(EleqtricField-V)_1/V*cm^-1) 4.3004+05 3.5838+05 2.867e+05 2.150e+05 1.433e+05 7.167e+04 0.0000e+00

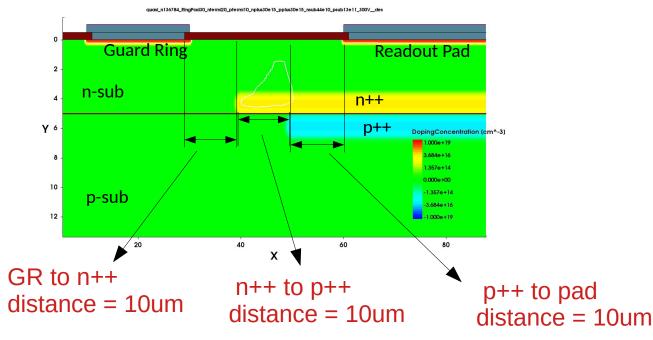
Symmetric termination:

- Lower field under the edge.
- Field lines are about to go around the edge.

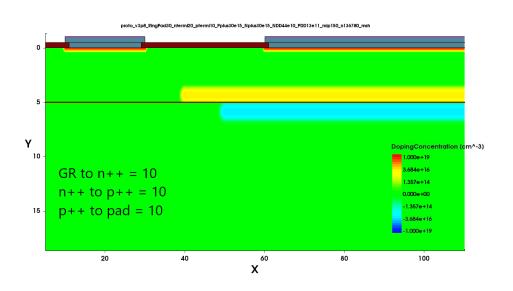


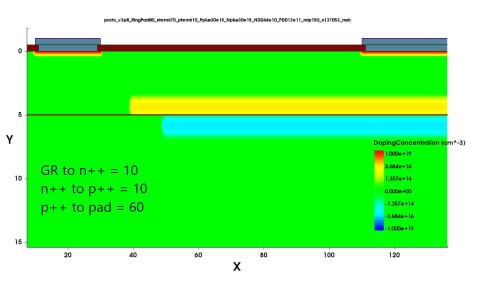
- Optimal Guard ring (GR) to pad distance, and the location of the gain layer termination are under investigation with simulation.
 - e.g. in the case of asymmetric termination, different distance of GR to n++, n++ to p++,
 p++ to pad are simulated. (see figure below for a 10/10/10 example)
 - Preliminary simulation studies show breakdown voltage varies with those parameters.





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 - Preliminary simulation studies show breakdown voltage varies with those parameters.
 - For example, Simulation was done with 10/10/10 (30um of GR to pad distance) and 10/10/60 (80um of GR to pad distance) asymmetric gain termination configuration.





Reversed Bias Voltage [V

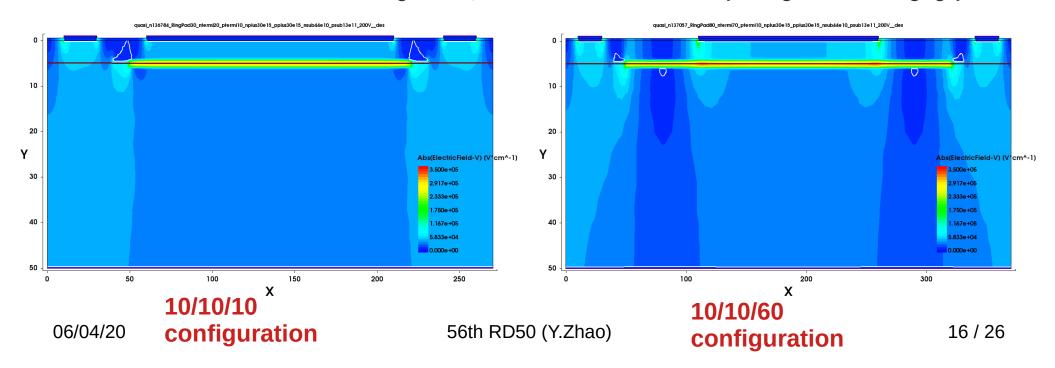
- Preliminary simulation studies show breakdown voltage varies with those parameters.
 - For example, Simulation was done with 10/10/10 (30um of GR to pad distance) and 10/10/60 (80um of GR to pad distance) asymmetric gain termination configuration.
 - I-V curve for the pad and left/right guard ring for these two configuration are different

10/10/60 configuration has a sign of early break down. Voltage point of sign of breakdown 1e-10 1e-11 1e-12 1e-06 10/10/60 configuration 1e-14 1e-08 Pad 1e-15 1e-16 Current/area Current 1e-10 Reversed Bias Voltage [V] 1e-12 10/10/10 configuration 1e-14 1e-11 1e-16 1e-13 -400 -300 -100 -200 Reversed Bias Voltage [V]

Left Guard Ring Current

Right Guard Ring Current

- Preliminary simulation studies show breakdown voltage varies with those parameters.
 - For example, Simulation was done with 10/10/10 (30um of GR to pad distance) and 10/10/60 (80um of GR to pad distance) asymmetric gain termination configuration.
 - I-V curve for the pad and left/right guard ring for these two configuration are different
 - 10/10/60 configuration has a sign of early break down
 - 2D electric map at 200V for these two configurations are shown
 - For 10/10/60 configuration, the field is lower in the GR-pad region due to large gap.

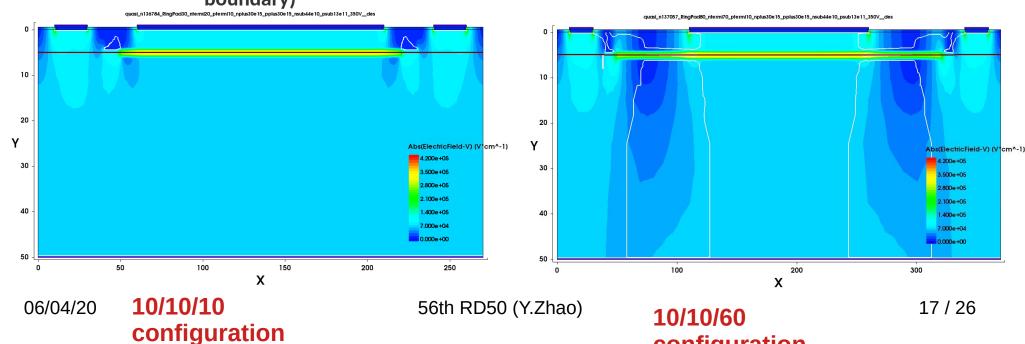


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10/10/60 configuration has a sign of early break down.

- 2D electric map map at 350V for these two configurations are shown
 - As indicated in the IV, 10/10/60 configuration has indication of breakdown beyond 250V. There's strange depleted region within the sensor (surround by the white lines boundary)

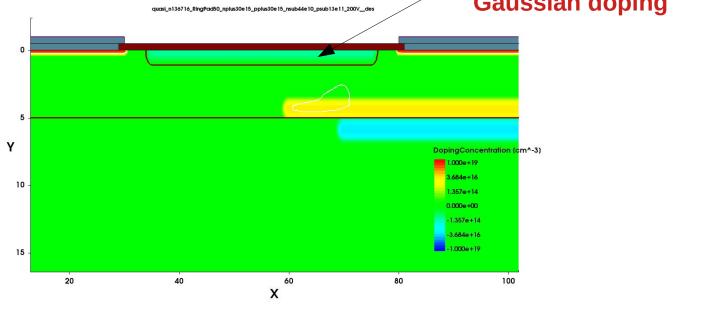
configuration



Current Stage of DJ-LGADP-Spray/Stop Between Guard Ring and Pad

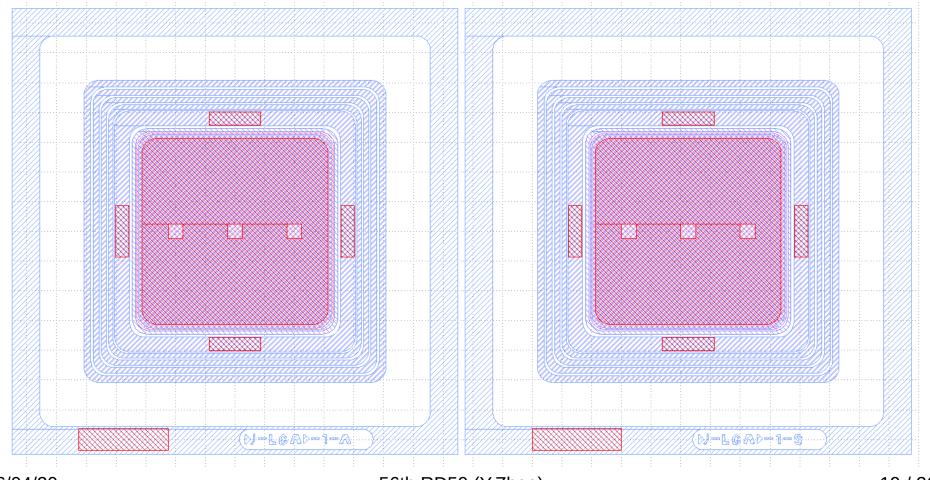
- Another simulation is to start looking into the adding p-spray/stop between the guard ring and the pad.
- A few parameters of p-spray/stop are requires more simulation studies:
 - P-spray/stop doping concentration level.
 - Width, or the distance between the p-spray and GR/pad.





Current Stage of DJ-LGADStarting GDS Mask/Layout Design

- We are also working on the GDS layout with Cactus Materials Inc.
- Example of top surface layout is shown below.



Summary and Next

- Simulation studies are ongoing for phase-1 prototype production.
- The production with Cactus Materials Inc is fully funded by DoE SBIR, and the first prototype is expected as the end of the year.
- Next:
 - Mask and layout design.
 - Continue on simulation studies:
 - Replace gain layer analytic doping with implantation simulation
 - Optimize the implant dosage for fabrication.
 - Optimize the guard ring and pad distance, and the location of gain termination.

Acknowledgments

• Institute of High Energy Physics (ihep, China) has provided helps on simulation.

Acknowledgments

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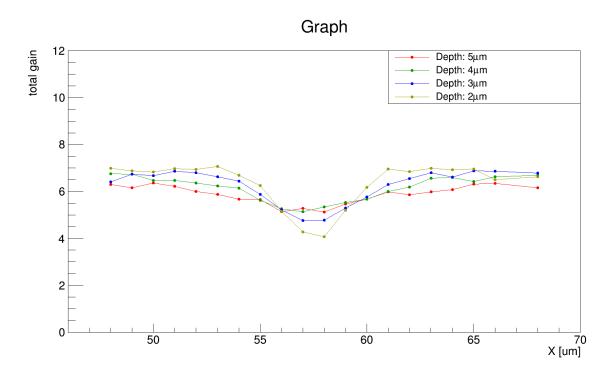
This project was supported in part by a Launchpad Grant awarded by the Industry Alliances & Technology Commercialization office from the University of California, Santa Cruz.

Backup

- Junction depth.
- Choice of wafer resistivity.
- MiP induced signal for nearby pads in arrays.

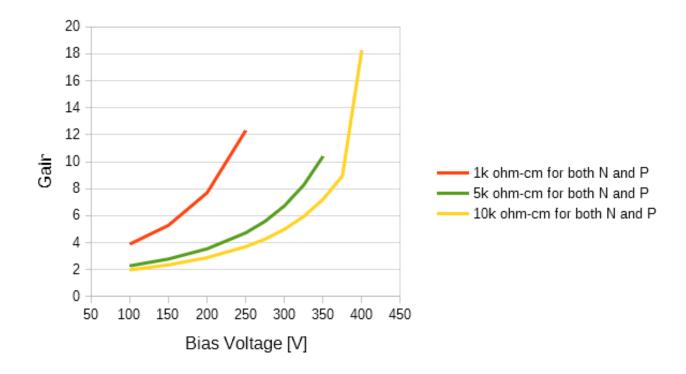
Current Stage of DJ-LGAD Junction depth

- Some MiP simulations for pixelated structure have been done with different junction depths.
- The gain uniformity across pads seems to related to the junction depth.
- For the phase-1, junction with 5um below the surface will be produced.



Current Stage of DJ-LGAD Choice of Wafer Resistivity

- Wafer of resistivity of a least $1k \Omega \cdot cm$ for both n and p type substrate.
- 10k Ω ·cm or above will be used for the phase-1 prototype.



Current Stage of DJ-LGADMiP induced signal for nearby Pads in Array

- The plot shown is with original DJ-LGAD design.
 - MiP is injected into one of the pad of a pixelated/array setup.

